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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/080,507	02/22/2002	Jae Chang Jung	00939B-068710US	1185	
. 20350	7590 10/27/2003		EXAM	EXAMINER	
TOWNSEND AND TOWNSEND AND CREW, LLP TWO EMBARCADERO CENTER			LEE, S	LEE, SIN J	
<b>EIGHTH FLO</b>	OR		ART UNIT	PAPER NUMBER	
SAN FRANCI	SCO, CA 94111-3834		1752		
			DATE MAILED: 10/27/2003	•	

Please find below and/or attached an Office communication concerning this application or proceeding.

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	Applicati n N .	Applicant(s)	. •
	10/080,507	JUNG ET AL.	
Offic Action Summary	Examiner	Art Unit	•
	Sin J Lee	1752	lrace
The MAILING DATE of this communication a Peri df r Reply	ppears n the cover sh	еет with the correspondence add	11 too
A SHORTENED STATUTORY PERIOD FOR REF THE MAILING DATE OF THIS COMMUNICATION  - Extensions of time may be available under the provisions of 37 CFR after SIX (6) MONTHS from the mailing date of this communication.  - If the period for reply specified above is less than thirty (30) days, a r  - If NO period for reply is specified above, the maximum statutory perions  - Failure to reply within the set or extended period for reply will, by state  - Any reply received by the Office later than three months after the material earned patent term adjustment. See 37 CFR 1.704(b).  Status	N. 1.136(a). In no event, however, eply within the statutory minimus od will apply and will expire SIX tute, cause the application to be	may a reply be timely filed  n of thirty (30) days will be considered timely.  (6) MONTHS from the mailing date of this concerned the concerned that the concerned th	mmunication.
1) Responsive to communication(s) filed on 2	<u> 2 February 2002</u> .		
,	This action is non-final		
3) Since this application is in condition for allo closed in accordance with the practice und	wance except for form er Ex parte Quavle 19	al matters, prosecution as to the 35 C.D. 11, 453 O.G. 213.	e merits is
Disposition of Claims		,	
4) Claim(s) 1-19 is/are pending in the applicat			•
4a) Of the above claim(s) is/are withd	Irawn from consideration	on.	
5) Claim(s) is/are allowed.			
6)⊠ Claim(s) <u>1-3 and 5-19</u> is/are rejected.			
7) Claim(s) is/are objected to.			
8) Claim(s) are subject to restriction and Application Papers	d/or election requireme	ent.	
9) The specification is objected to by the Exam	iner.		
10) ☐ The drawing(s) filed on 22 February 2002 is/		objected to by the Examiner.	
Applicant may not request that any objection to			
11) The proposed drawing correction filed on			er.
If approved, corrected drawings are required in	reply to this Office action	١.	
12) The oath or declaration is objected to by the	Examiner.	· ·	
Pri rity under 35 U.S.C. §§ 119 and 120	•	·	
13) Acknowledgment is made of a claim for fore	eign priority under 35 L	I.S.C. § 119(a)-(d) or (f).	
a)⊠ All b) Some * c) None of:			
<ol> <li>Certified copies of the priority docum</li> </ol>			
2. Certified copies of the priority docum			
<ul> <li>3. Copies of the certified copies of the papplication from the International</li> <li>* See the attached detailed Office action for a</li> </ul>	Bureau (PCT Rule 17	2(a)).	Stage
14) Acknowledgment is made of a claim for dom			l application).
a) ☐ The translation of the foreign language 15)☐ Acknowledgment is made of a claim for dom	provisional application	has been received.	•
Attachment(s)			
<ol> <li>Notice of References Cited (PTO-892)</li> <li>Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>Information Disclosure Statement(s) (PTO-1449) Paper Notes</li> </ol>	) 5) 🔲 N	terview Summary (PTO-413) Paper No otice of Informal Patent Application (PT ther:	

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### **DETAILED ACTION**

# Claim Rejections - 35 USC § 102

1. The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

(b) the invention was patented or described in a printed publication in this or a foreign country or in public use or on sale in this country, more than one year prior to the date of application for patent in the United States.

2. Claims 1-3, 5-7, and 10-19 are rejected under 35 U.S.C. 102(b) as being anticipated by Kajita et al (6,180,316 B1).

Kajita, in his Synthesis Example 8, teaches a copolymer (A-4) made from the monomers of 5-t-butoxycarbonylnorbornene, 8-methyl-8-hydroxymethyltetracyclo[4.4.0.1<sup>2,5</sup>.1<sup>7,10</sup>]dodec-3-ene, maleic anhydride, and 2,5-dimethyl-2,5-hexanediol diacrylate, and the chemical structure for the copolymer is shown in col.34, lines 45-col.35, lines 1-20. Kajita's copolymer of Synthesis Example 8 teaches present copolymer of <Chemical Formula 5> of present claim 3: The repeating unit (20-2) of Kajita's copolymer teaches present repeating unit a of the Formula 5 because present R<sub>1</sub>, R<sub>2</sub>, R<sub>5</sub>, and R<sub>6</sub> can all be hydrogen atoms, present R<sub>3</sub> can be a methyl group (which is a straight C<sub>1</sub> alkyl group), and present R<sub>4</sub> can be –CH<sub>2</sub>OH (which is a straight C<sub>1</sub> alkyl group including one hydroxyl group). The repeating unit (20-3) of Kajita's copolymer teaches present repeating unit b of the Formula 5. The repeating unit (20-4) of Kajita's copolymer teaches present repeating unit c of the formula 5

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because present R' and R" can both be hydrogen atoms and present R can be a branched C<sub>8</sub> alkyl group. Kajita furthermore teaches the mol% for the repeating unit (20-2) to be 9 mol%, the mol% for the repeating unit (20-3) to be 45 mol%, and the mol% for the repeating unit (20-4) to be 10 mol%. These numbers fall within the present ranges of claim 3. Therefore, Kajita teaches present inventions of claims 1-3 and 5.

With respect to present claims 6, 7, and 10, in his Synthesis Example 8, Kajita carries out the polymerization reaction for 8 hours at 70°C in a *nitrogen* stream in the presence of *azobisisobutyronitrile* (polymerization initiator). Therefore, the prior art teaches present inventions of claims 6, 7, and 10.

In Examples 6-8, Kajita uses his copolymer (A-4) made in his Synthesis Example 8 together with an organic solvent, and a photoacid generator. Therefore, the prior art teaches present inventions of claims 11 and 12. Kajita teaches triphenylsulfonium trifluoromethanesulfonate (which is the presently claimed triphenylsulfonium triflate in claim 13) as one of six examples of the photoacid generators used in his working examples. Since there are only several examples to choose from, it is the Examiner's position that one of ordinary skill in the art would immediately envisage using triphenylsulfonium trifluoromethanesulfonate as Kajita's photoacid generator.

Therefore, the prior art teaches present invention of claim 1.

Kajita teaches (col.23, lines 18-37) that his photoresist composition is applied on a silicone wafer. The resist film thus prepared is optionally subjected to a prebaking treatment, then exposed to radiation (such as ArF excimer laser or KrF excimer laser) to

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form a resist pattern. The exposed resist film is then subjected to a post-exposure baking treatment which is carried out at a temperature usually from 30 to 200°C. Because 200°C is included as the higher end of the taught range, it is the Examiner's position that one of ordinary skill in the art would immediately envisage carrying the post-exposure baking step at 200°C in Kajita's invention. A desired resist pattern is then formed by developing the exposed areas on the resist film using an alkaline aqueous developer solution such as tetramethylammonium hydroxide (col.23, lines 48-59). Therefore, the prior art teaches present inventions of claims 14-18. Kajita also teaches (col.28, lines 27-37) that his photoresist composition is an ideal material for the manufacture of semiconductor devices. Therefore, the prior art also teaches present invention of claim 19.

## Claim Rejections - 35 USC § 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claims 8 and 9 are rejected under 35 U.S.C. 103(a) as being unpatentable over Kajita et al (6,180,316 B1).

With respect to present claim 8, the polymerization reaction in Kajita's Synthesis Example 8 is carried out in a nitrogen stream (as discussed above) which inherently

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would have a certain pressure. Although Kajita does not disclose what the pressure was, one of ordinary skill in the art repeating Kajita's experiment would be motivated to use a nitrogen pressure resulting in formation of the desired product. It is the Examiner's position that this pressure would lie within the very broadly claimed present range of 0.0001-5 atm. Therefore, present claim 8 is obvious over Kaiita.

With respect to present claim 9, although Kajita uses 1,2-diethoxyethane as the solvent for the polymerization reaction in his Synthesis Example 8, Kajita also teaches (col.16, lines 10-20) the equivalence of 1,2-diethoxyethane to the presently claimed benzene or toluene. Because these solvents were art-recognized equivalents at the time the invention was made, one of ordinary skill in the art would have found it obvious to replace 1,2-diethoxyethane with benzene or toluene in Kajita's Synthesis Example 8 with a reasonable expectation of achieving a photosensitive resin composition exhibiting high transparency to radiation, superior dry-etching resistance, high resolution, and an excellent property balance. Therefore, Kajita's teaching would render obvious present invention of claim 9.

#### Allowable Subject Matter

5. Claim 4 is objected to as being dependent upon a rejected base claim, but would be allowable if rewritten in independent form including all of the limitations of the base claim and any intervening claims. Kajita does not teach or suggest presently claimed polymers of claim 4.

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pm EST.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Sin J. Lee whose telephone number is (703) 305-0504. The examiner can normally be reached on Monday-Friday from 8:30 am EST to 5:00

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Ms. Janet Baxter, can be reached on (703) 308-2303. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9311 for after final responses or (703) 872-9310 for before final responses.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 305-0661.

S-A.L

S. Lee 10/17/03

JANET BAXTER

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